

# Reducing Residual Resistance at Operating Fields: Potential, Challenges, and Future R&D Directions

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**Jefferson Lab**



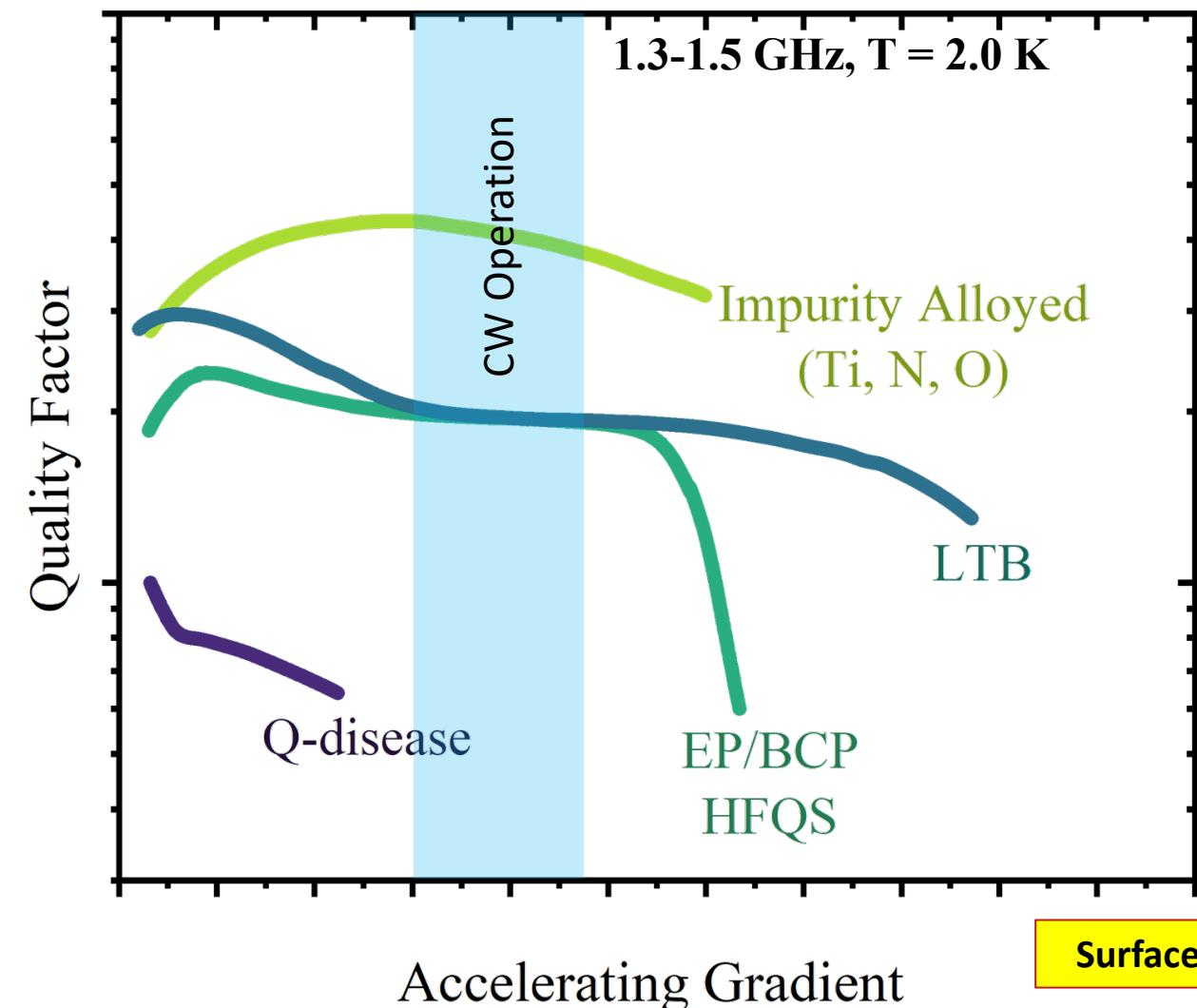
**U.S. DEPARTMENT  
of ENERGY**



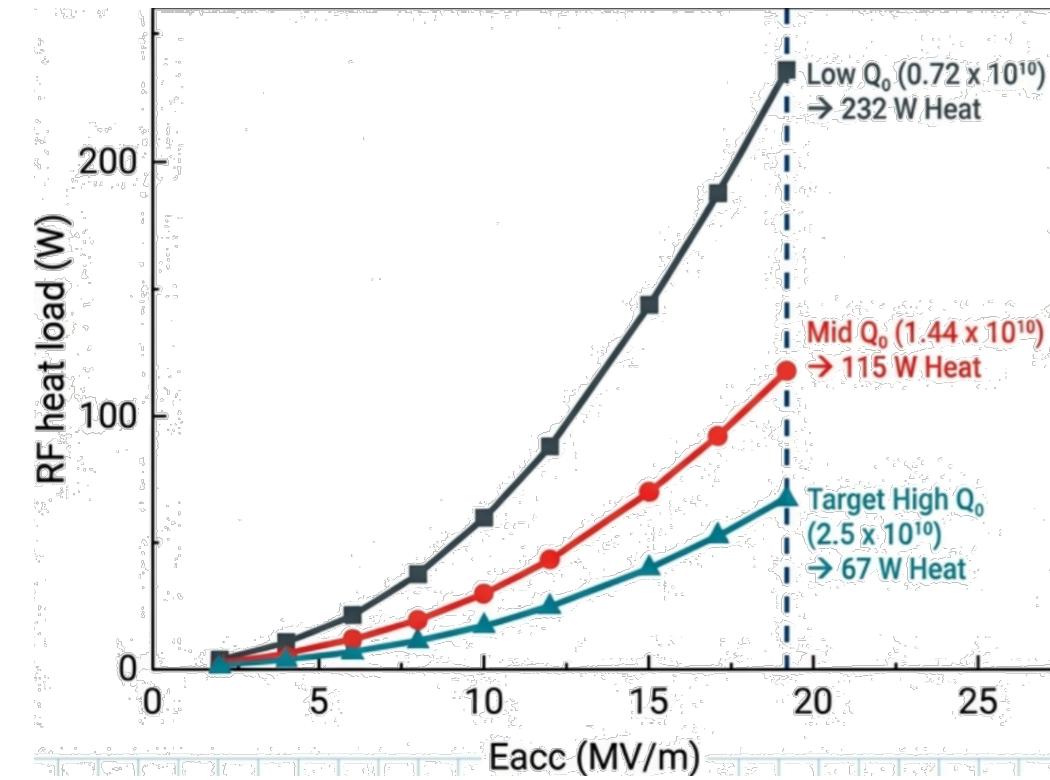
# OUTLINE

- Current Status of SRF R&D
- High Q, High Gradient
- Potential, Challenges, and Future R&D Directions

# CURRENT STATUS OF SRF R&D



$$P_{RF} = (E_{acc})^2 \left( \frac{R_s}{G} \right) \left( \frac{1}{R/Q} \right)$$



Surface resistance is not just a material parameter; it is an operating expense.

# SURFACE RESISTANCE

$$R_s(T, B_{rf}) = R_{BCS}(T, B_{rf}) + R_0(B_{rf})$$

- **Counter-Intuitive Physics:**

Pure Niobium is not the theoretical optimum.

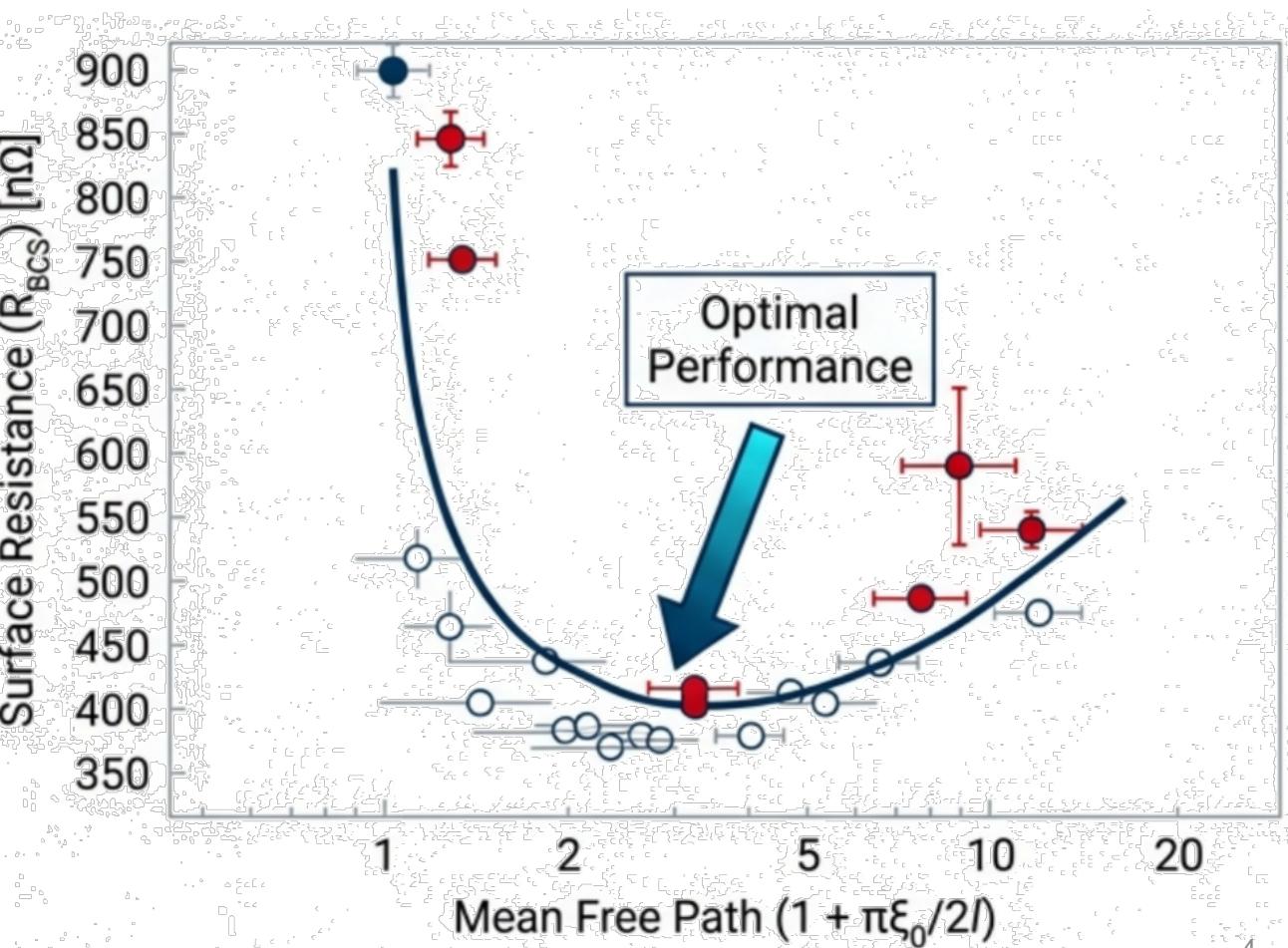


- **The Mechanism:**

By introducing impurities (doping), we shorten the electron mean free path.



- **The Result:** Resistance reaches a minimum when the coherence length matches the mean free path ( $\xi_0/\ell \approx 1$ ).



# RESIDUAL RESISTANCE ( $R_0$ )

$R_{\text{interstitial}}$ : Caused by material impurities (H, N, C). Addressed by high RRR.

$R_{\text{interface}}$ : Substrate effects, typically for bimetallic structures.

$R_{\text{suboxide}}$ : Surface oxides ( $\text{NbO}_2$ ,  $\text{NbO}$ ). Addressed by annealing.

$$R_0 = R_{\text{interstitial}} + R_{\text{suboxide}} + R_{\text{TLS}} + R_{\text{interface}} + R_{\text{flux}} + R_{\text{surfacedefects}} + \dots$$

$R_{\text{TLS}}$ : Two-Level Systems due to  $\text{Nb}_2\text{O}_5$  (at  $T < 1$  K). Addressed by Annealing/Capping.

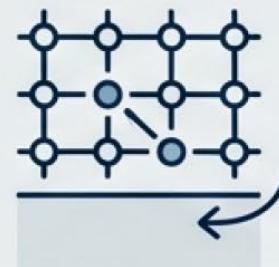
$R_{\text{surfacedefects}}$ : Surface damage. Addressed by Chemical/Mechanical Polishing.

$R_{\text{flux}}$ : Trapped Flux. Addressed by shielding and cooldown protocols.

# HIGH $Q_0$ , HIGH GRADIENT

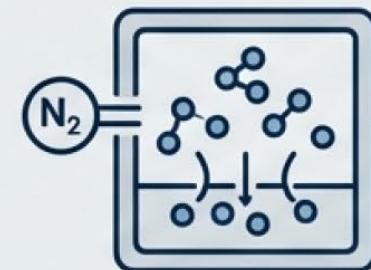
## The Recipe: Surface Alloying within the RF Penetration Depth

### Titanium Doping



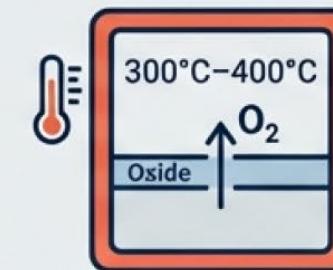
Surface alloying with Ti.

### Nitrogen Doping/Infusion



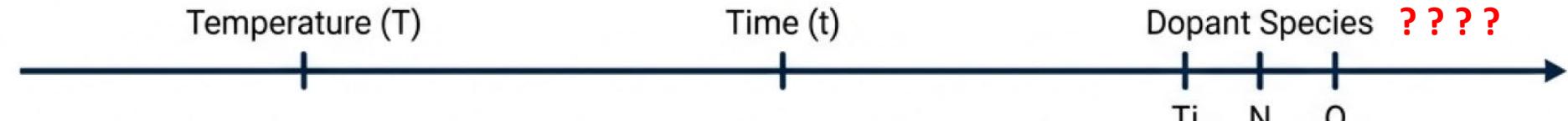
High-temperature furnace treatment with  $N_2$  gas.

### Oxygen (Mid-T Bake)



Baking at 300°C–400°C to diffuse native oxide layers.

### Process Variables

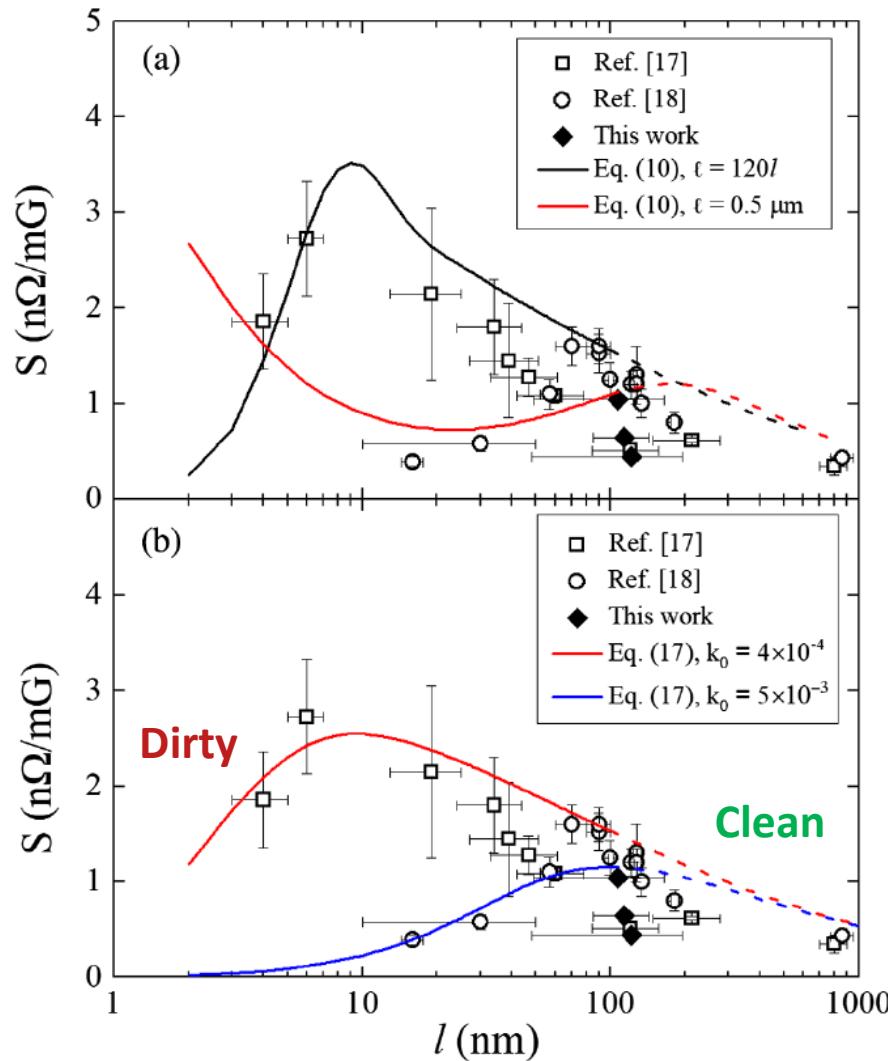


- $Q$ -rise is due to the current-induced broadening of the quasiparticle density of states in dirty limit. *Gurevich, PRL 2014*
- High  $Q_0$  cavities are very sensitive to trapped magnetic flux during cooldown, often mask the benefit of high  $Q_0$

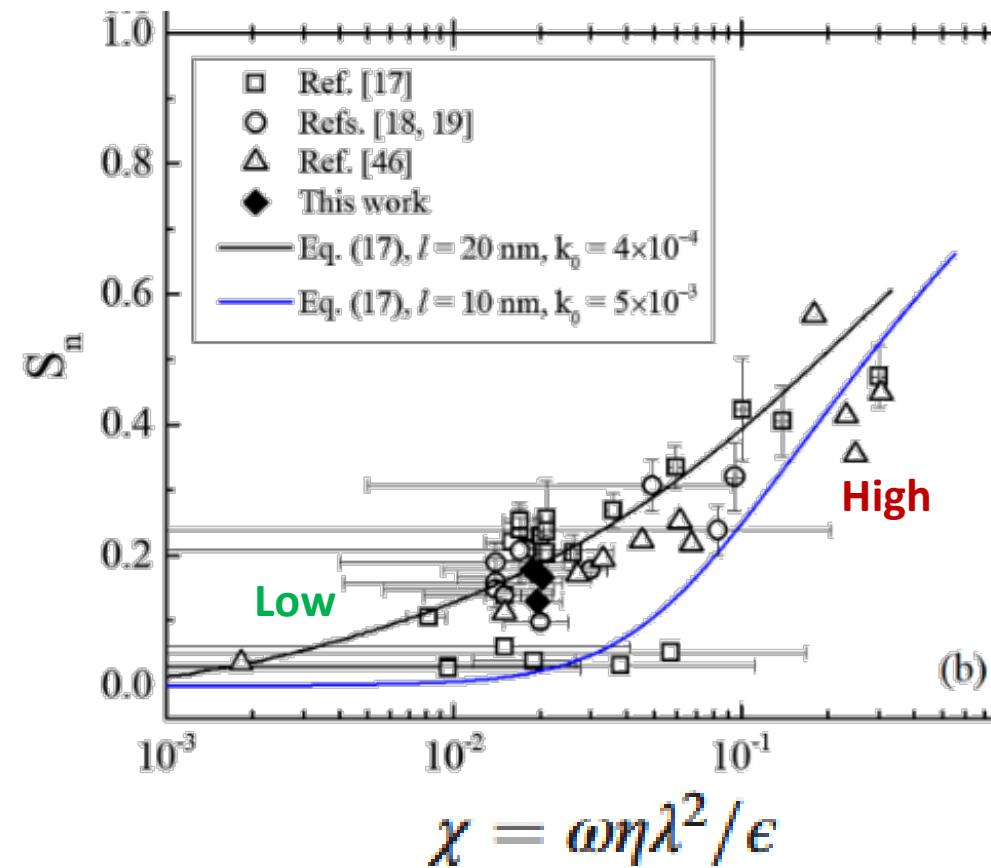
# RESIDUAL RESISTANCE ( $R_0$ )

$$R_0 = R_{\text{interstitial}} + R_{\text{suboxide}} + R_{\text{TLS}} + R_{\text{interface}} + \boxed{R_{\text{flux}}} + R_{\text{surfacedefects}} + \dots$$

# FLUX TRAPPING (LOW FIELD)



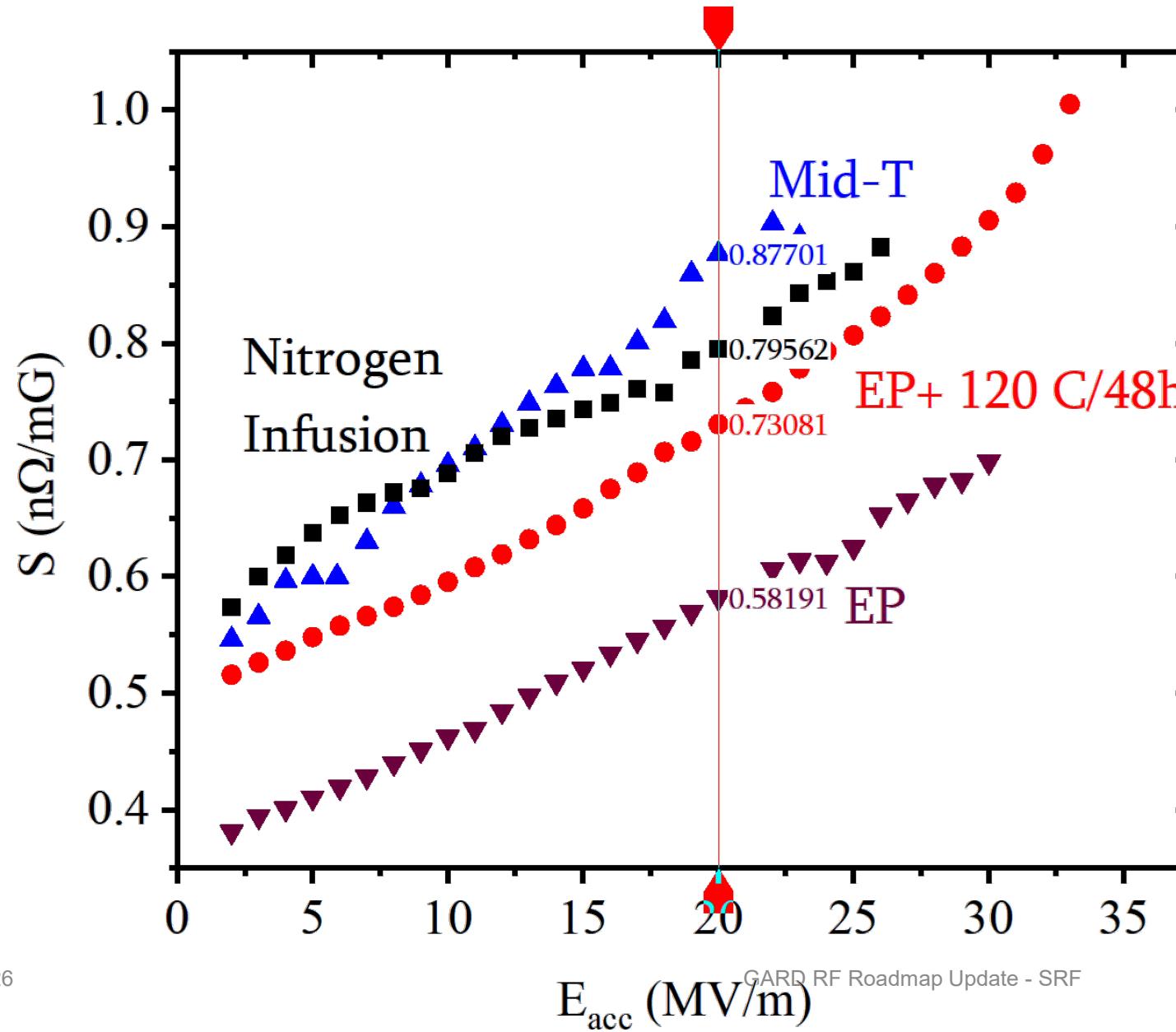
P. Dhakal *et al.*, PRAB, 23, 023102 (2020)  
A. Gurevich, SUST, 30, 034004 (2017)



Flux trapping sensitivity depends on

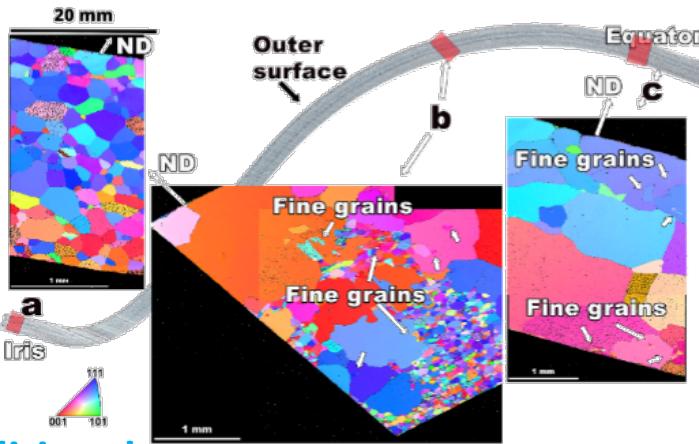
- Mean free path
- Pinning strength/type
- Frequency
- Orientation of flux lines with respect to rf field

# FLUX TRAPPING-FIELD DEPENDENCE



# FLUX EXPULSION/TRAPPING/RECRYSTALLIZATION

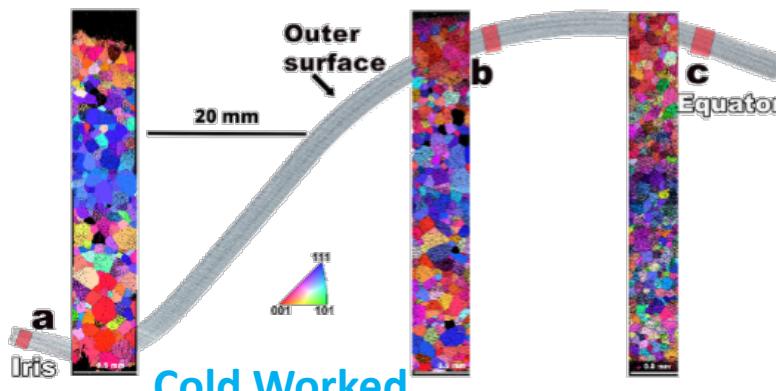
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Traditional

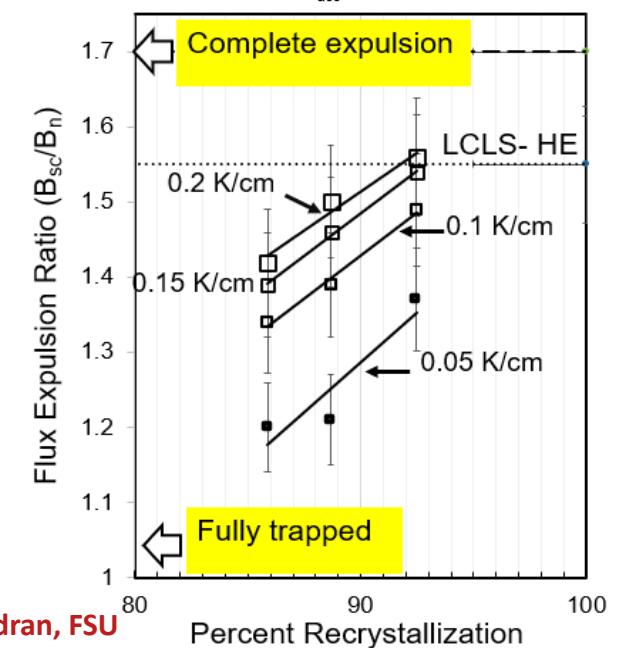
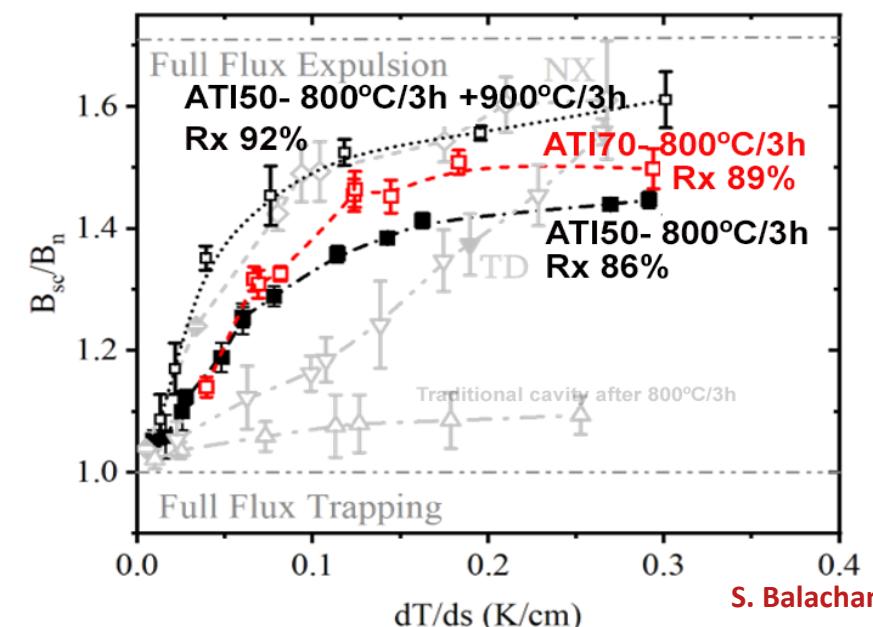
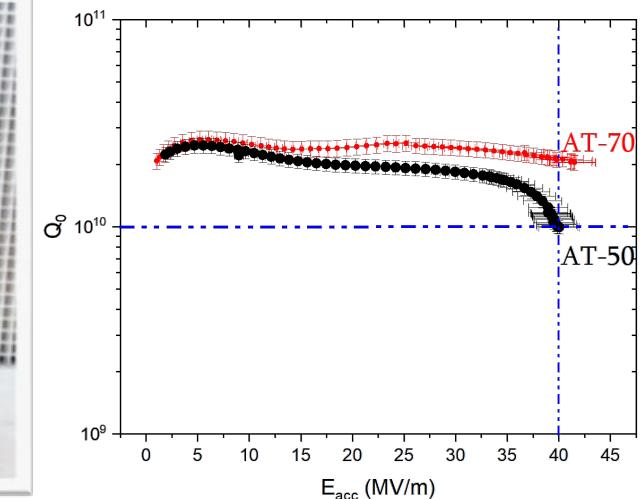
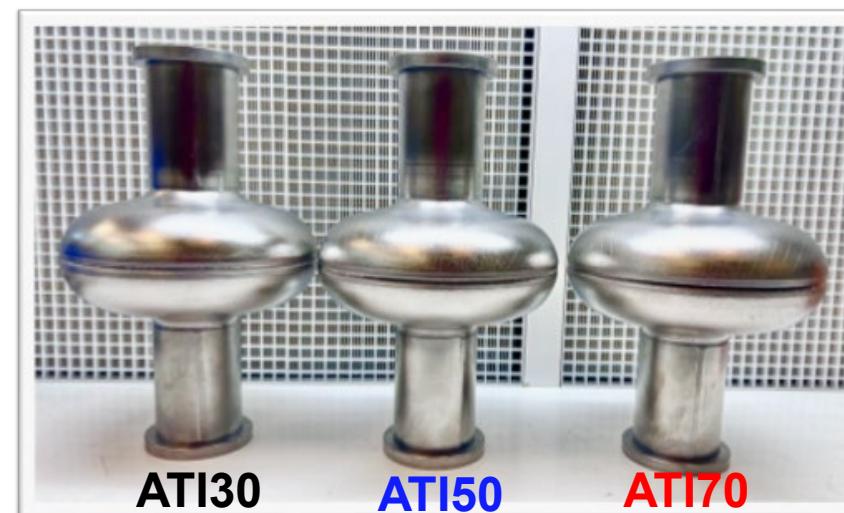
Cavities fabricated from cold-worked Nb sheets, followed by heat treatment at 800°C shown to

**Improved flux expulsion** compared to traditional methods



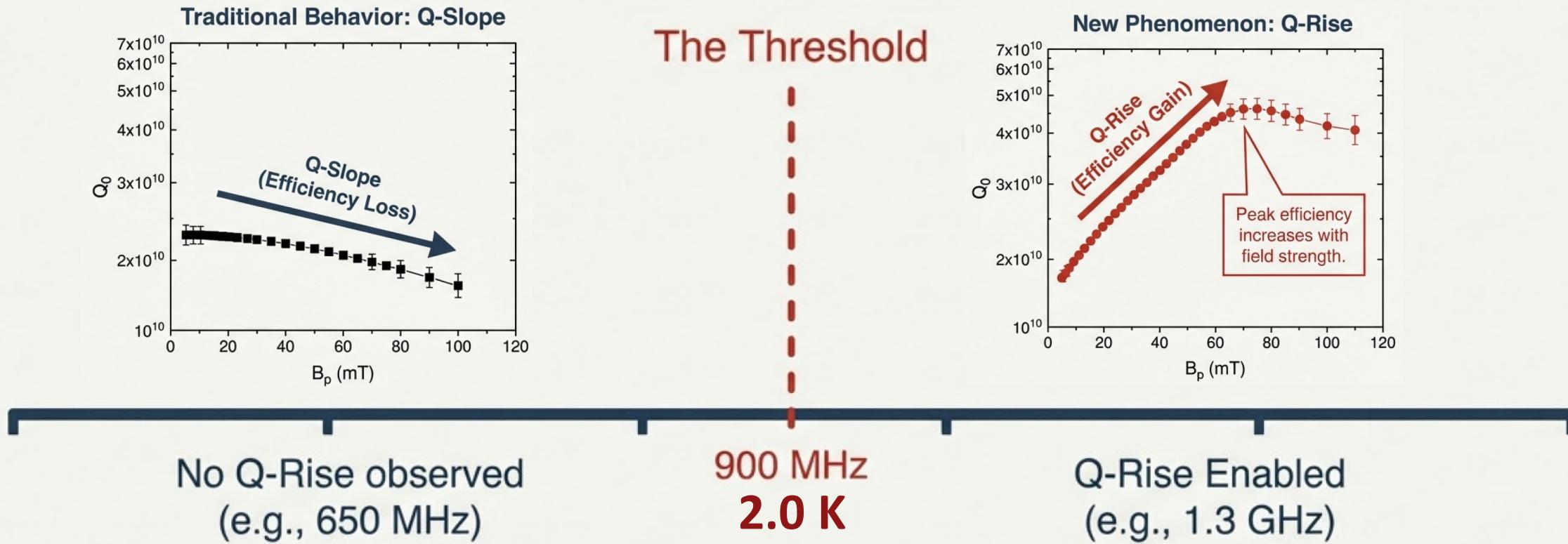
Cold Worked

2/5/2026



**The main source of  
surface resistance at operating gradient is  
due to residual flux trapping  
during cooldown**

# $Q_0$ -RISE & FREQUENCY DEPENDENCE

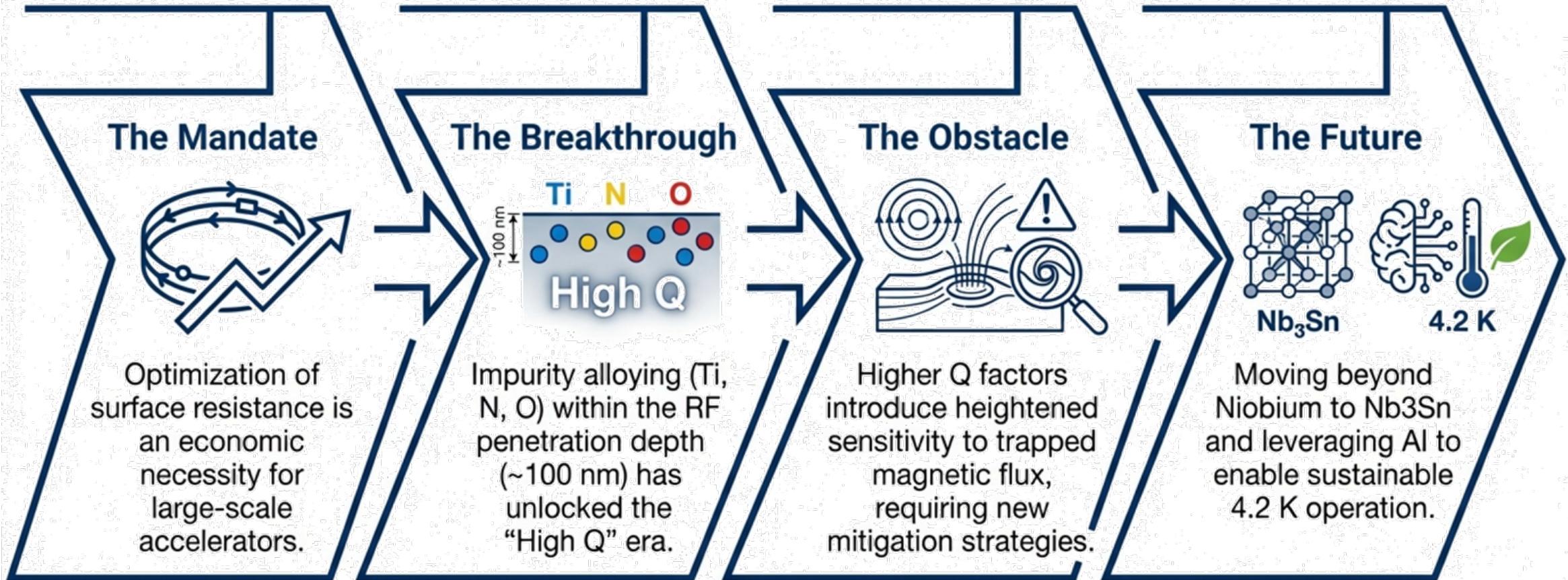


## Theoretical Model: Non-Equilibrium Superconductivity

A race between the RF drive and electron relaxation.

Gurevich, SUST (2023)  
Kubo & Gurevich, PRB 100, 064522 (2019)  
Kaplan et al., PRB 14, 4854 (1976)

# The Path to Next-Generation SRF Performance



**Mastering nanoscale surface physics to enable miles long discovery**

# Questions?